

# **IN-LINE DEPOSITION PROCESSES FOR THIN FILM BATTERY FABRICATION**

## **ABSTRACT**

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In one embodiment, the invention is directed to aperture mask deposition techniques using aperture mask patterns formed in one or more elongated webs of flexible film. The techniques involve sequentially depositing material through mask patterns formed in the film to define layers, or portions of layers, of the thin film battery. A

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deposition substrate can also be formed from an elongated web, and the deposition substrate web can be fed through a series of deposition stations.